

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Patent Application**

Applicant(s): Roger Y.B. Young et al.  
Serial No.: 10/628,614  
Filing Date: July 28, 2003  
Confirm. No.: 4439  
Art Unit: 2878  
Examiner: Que Tan Le

Title: Wafer Edge Defect Inspection Using Captured Image Analysis

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AMENDMENT AND RESPONSE TO OFFICE COMMUNICATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313

Sir:

In response to the outstanding Office Communication dated March 24, 2011, Applicants respectfully request reconsideration of the above-identified application in view of the amendments made herein.